

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : FRANK-MICHAEL KAMM ET AL.
Filed : CONCURRENTLY HEREWITH
Title : REFLECTIVE MIRROR FOR LITHOGRAPHIC EXPOSURE AND PRODUCTION METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

European Patent Application EP 1 065 532 A2 (Singh), dated January 3, 2001;

Morita, M. et al.: "Native Oxide Growth on Silicon Surface in Wet Ambient", Extended Abstract of the 22nd Conference on Solid State Devices and Materials, 1990, pp. 1063-1066;

Yasaka, T. et al.: "Layer-By-Layer Oxidation of Silicon", Materials Research Society Proc., Vol. 222, 1991, pp. 225-230;

Morita, M. et al.: "Control Factor of Native Oxide Growth on Silicon Surface in Air or in Ultrapure Water", Appl. Phys. Lett. 55 (6), American Institute of Physics, August 7, 1989, pp. 562-564.

Respectfully submitted,

For Applicants

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Date: August 1, 2003

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FORM PTO-1449 (SUBSTITUTE)				Attorney Docket No.: P2002,0645 Appl. No.: _____			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE							
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Applicant: FRANK-MICHAEL KAMM ET AL.			
				Filing Date: August 1, 2003 Group Art Unit:			

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						

FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
	J	1 065 532 A2	1/3/01	Europe			
	K						
	L						
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	Morita, M. et al.: "Native Oxide Growth on Silicon Surface in Wet Ambient", Extended Abstract of the 22 nd Conference on Solid State Devices and Materials, 1990, pp. 1063-1066
	Yasaka, T. et al.: "Layer-By-Layer Oxidation of Silicon", Materials Research Society Proc., Vol. 222, 1991, pp. 225-230
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EXAMINER	DATE CONSIDERED